VE 320 Summer 2019

Introduction to Semiconductor Devices

Instructor: Rui Yang (杨睿)

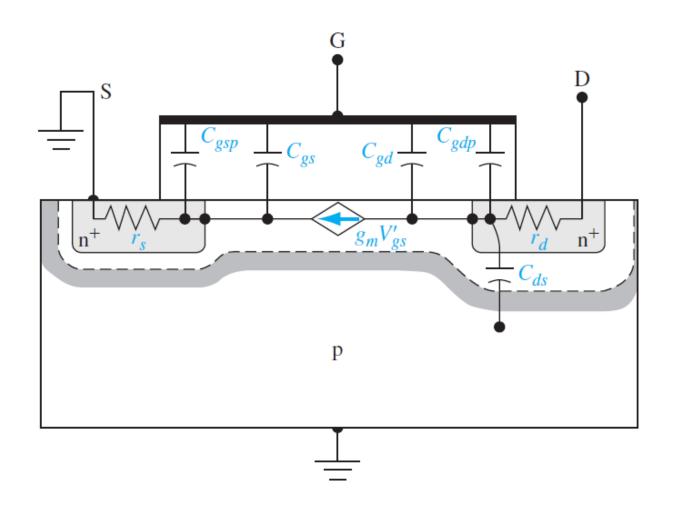
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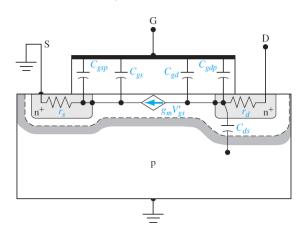


Lecture 13

MOSFET (Chapter 10 & 11)

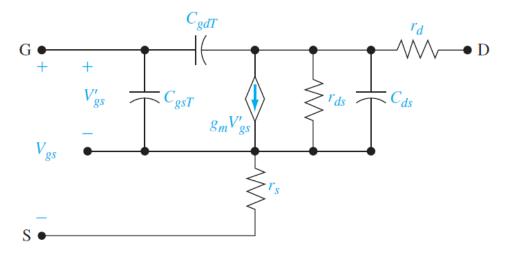


Frequency limitation & cutoff frequency

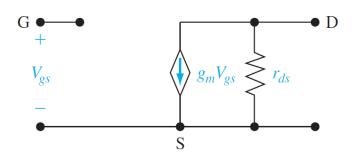


 $C_{\rm gs}$, $C_{\rm gd}$: interaction between the gate and the channel charge near the source and drain terminals $C_{\rm gsp}$, $C_{\rm gdp}$: parasitic capacitance, due to overlap of the gate area and source/ drain area – Need to minimize this in real devices to get higher frequency/ speed $g_{\rm m}V_{\rm gs}$ ': current source, controlled by the gate voltage

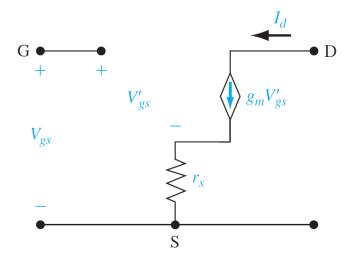
Small-signal equivalent circuit:



Simplified small-signal equivalent circuit at low frequency:



Common source NMOSFET Ignored series resistances



Common source NMOSFET Include source resistance r_s

$$I_d = g_m V'_{gs}$$

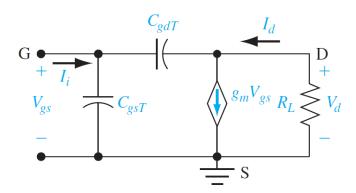
$$V_{gs} = V'_{gs} + (g_m V'_{gs}) r_s = (1 + g_m r_s) V'_{gs}$$

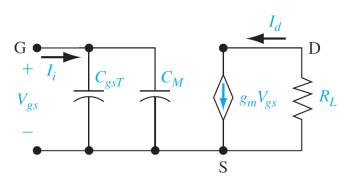
$$I_d = \left(\frac{g_m}{1 + g_m r_s}\right) V_{gs} = g'_m V_{gs}$$

What is limiting the frequency of MOSFETs?

Carrier travel velocity? 10^7 cm/s, need 10 ps to travel 1 μ m \rightarrow 100GHz! Not the limiting factor

Capacitance charging!





Input:
$$I_i = j\omega C_{gsT}V_{gs} + j\omega C_{gdT}(V_{gs} - V_d)$$

Output:
$$\frac{V_d}{R_L} + g_m V_{gs} + j\omega C_{gdT} (V_d - V_{gs}) = 0$$

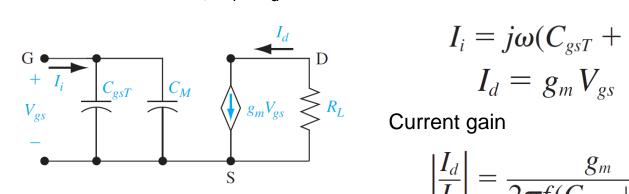
$$I_i = j\omega \left[C_{gsT} + C_{gdT} \left(\frac{1 + g_m R_L}{1 + j\omega R_L C_{gdT}} \right) \right] V_{gs}$$
 $\omega R_L C_{gdT}$ «1

$$I_i = j\omega [C_{gsT} + C_{gdT}(1 + g_mR_L)]V_{gs}$$
 $C_M = C_{gdT}(1 + g_mR_L)$ Miller capacitance

Drain overlap parasitic capacitance: important Multiplied by gain $g_{\rm m}$



Cutoff frequency f_T : the frequency at which the magnitude of the current gain of the device is unity, $I_i = I_d$



$$I_i = j\omega(C_{gsT} + C_M)V_{gs}$$
$$I_d = g_m V_{gs}$$

$$\left|\frac{I_d}{I_i}\right| = \frac{g_m}{2\pi f(C_{gsT} + C_M)}$$

$$f_T = \frac{g_m}{2\pi (C_{gsT} + C_M)} = \frac{g_m}{2\pi C_G}$$

Ideal MOSFET in saturation: no parasitic, $C_{\rm gd}$ small in saturation, $C_{\rm gd}$ is $C_{\rm ox}WL$

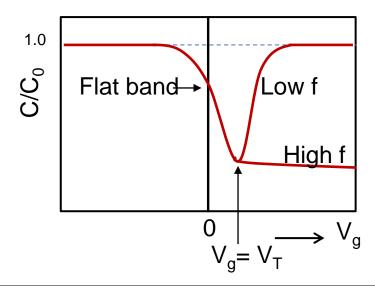
$$g_{ms} = \frac{W\mu_n C_{ox}}{L} (V_{GS} - V_T)$$
 High mobility \rightarrow High speed

$$f_T = \frac{g_m}{2\pi C_G} = \frac{W\mu_n C_{\text{ox}}}{L} (V_{GS} - V_T) = \frac{\mu_n (V_{GS} - V_T)}{2\pi L^2}$$



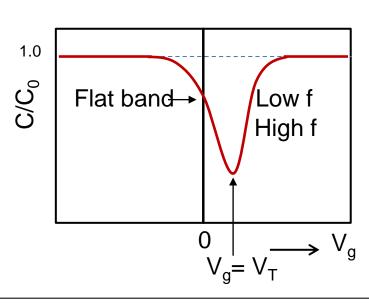
CV difference between MOS Capacitor and MOSFET

CV of MOS capacitor



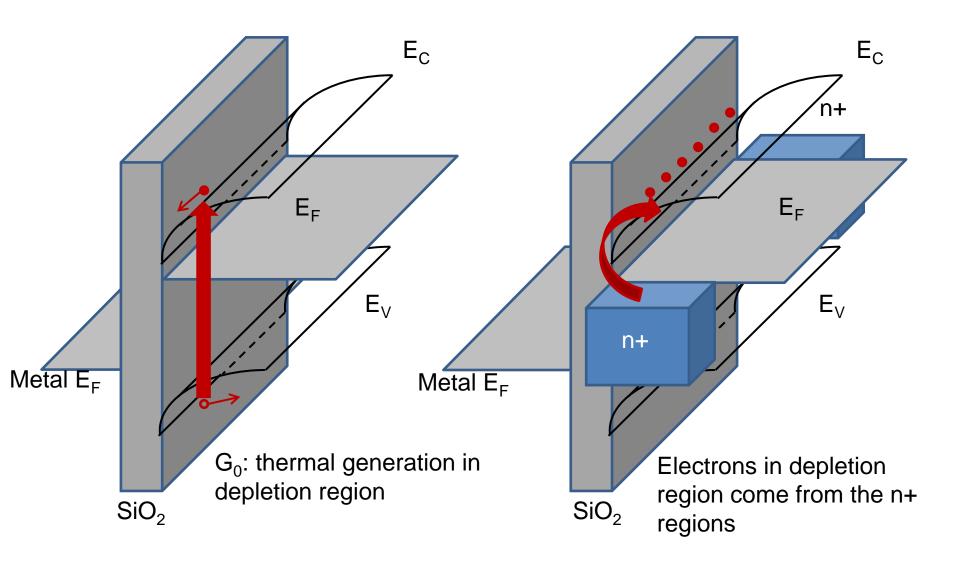
Inversion electrons come from electron generation from valance band which is slow. At high frequency, electron generation will be frozen out. Without inversion electrons, the capacitance will remain low.

CV of MOSFET



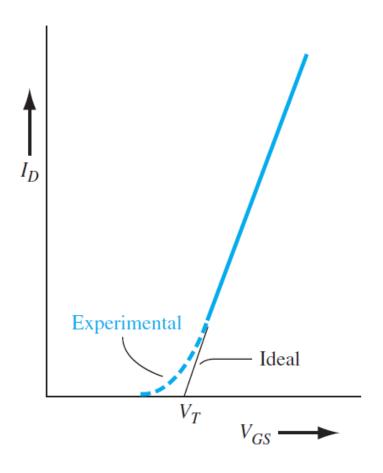
Electrons in the channel come from source and drain electrons. At high frequency, these electrons can move fast enough to respond to the gate electrode frequency.

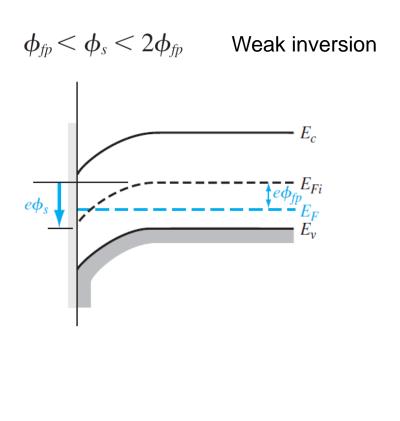
Band structure of MOS Capacitor and MOSFET



MOSFET: Nonideal effects

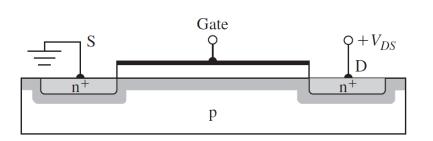
Subthreshold leakage: drain current when $V_{GS} \le V_{T}$

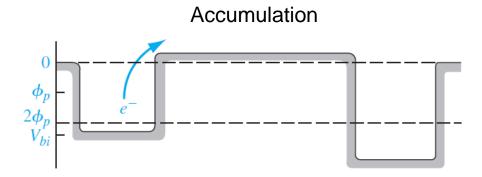


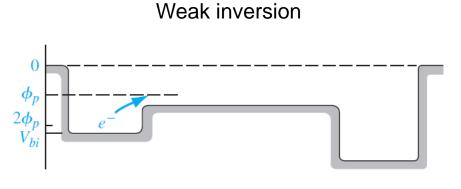


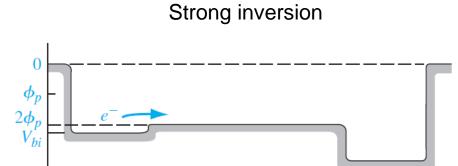
MOSFET: Nonideal effects

Subthreshold leakage: drain current when $V_{GS} \le V_{T}$







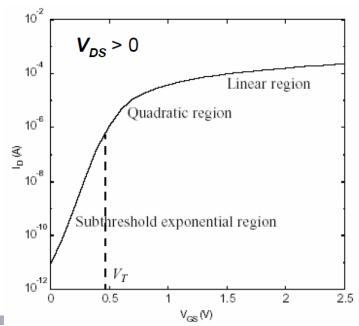


Subthreshold Conduction (Leakage Current)

- The transition from the ON state to the OFF state is gradual. This can be seen more clearly when I_D is plotted on a logarithmic scale:
- In the subthreshold (V_{GS} < V_T) region,

Large
$$V_{\rm DS}$$
:
$$I_{D} \propto \exp\left(\frac{qV_{GS}}{nkT}\right)$$

This is essentially the channelsource pn junction current. (Some electrons diffuse from the source into the channel, if this pn junction is forward biased.)

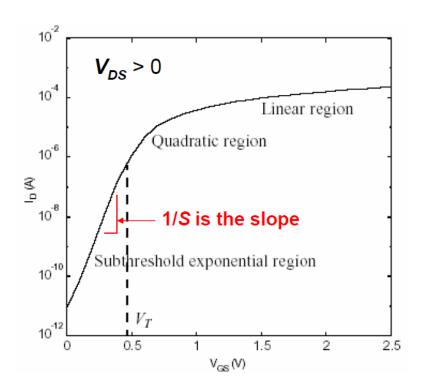


$$I_D(\text{sub}) \propto \left[\exp\left(\frac{eV_{GS}}{kT}\right) \right] \cdot \left[1 - \exp\left(\frac{-eV_{DS}}{kT}\right) \right]$$

Small V_{DS}

Slope Factor (or Subthreshold Swing) S

• S is defined to be the inverse slope of the log (I_D) vs. V_{GS} characteristic in the subthreshold region:



$$S \equiv n \left(\frac{kT}{q}\right) \ln(10)$$
 Ideally, n=1

Units: Volts per decade

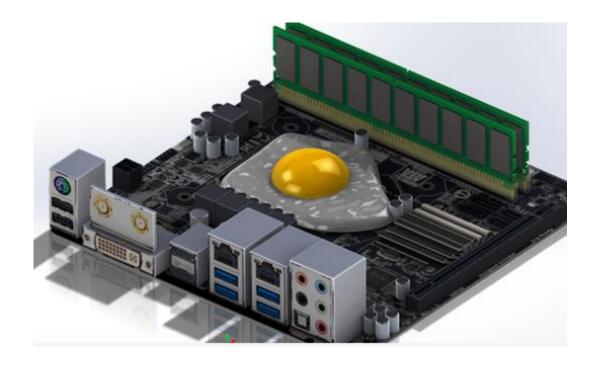
Note that $S \ge 60$ mV/dec at room temperature:

$$\left(\frac{kT}{q}\right)\ln(10) = 60 \,\text{mV}$$
"Boltzmann limit"

In reality, usually larger than 60mV/dec due to semiconductor doping and interface state



 Subthreshold leakage: lead to power dissipation in the "off" state



- Subthreshold leakage: lead to power dissipation in the "off" state (Want to turn off at 0V)
- Want large subthreshold slope, or small subthreshold swing S
- Dynamic power dissipation $P_{\rm dyn} \propto V_{\rm DD}^2$
- Want to decrease V_{DD}
- Need to reduce V_T to remain large enough I_{ON}
- Lower V_T : larger off-state power dissipation P_{OFF}
- Small S: can decrease $V_{\rm DD}$ and $V_{\rm T}$ together, ideally S=0
- Limited by the MOSFET operating mechanism in the subthreshold region
- How to minimize the subthreshold leakage/ decrease the subthreshold swing?



V_T Design Trade-Off

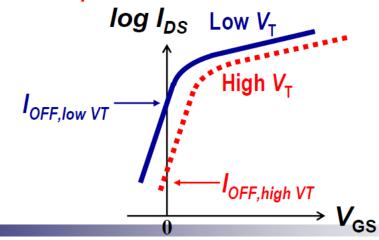
(Important consideration for digital-circuit applications)

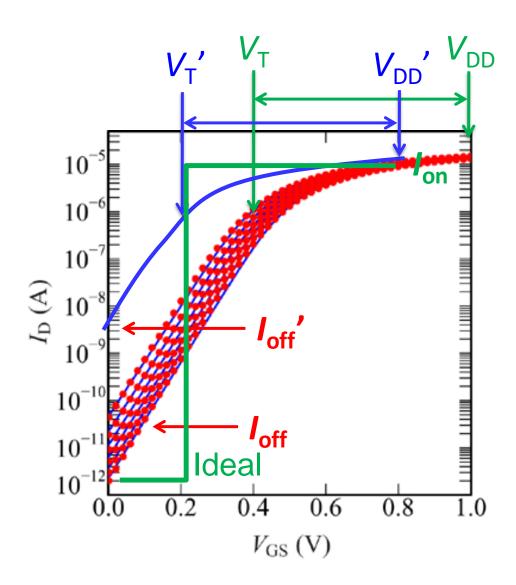
■ Low V_T is desirable for high ON current

$$I_{DSAT} \propto (V_{DD} - V_T)^{\eta} \qquad 1 < \eta < 2$$

where V_{DD} is the power-supply voltage

...but high V_T is needed for low OFF current





Need Steep Subthreshold Slope Switches!

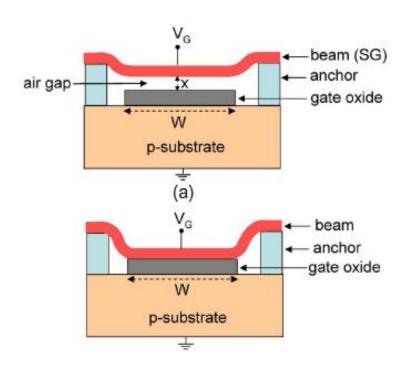
- New device technology to reduce subthreshold swing S
 - Microelectromechanical systems (MEMS) and nanoelectromechanical systems (NEMS) switch
 - Tunneling transistor
 - Negative capacitance transistor
 - Spin, photon

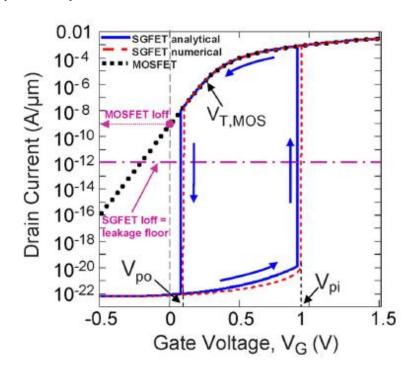
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Still in active research

Microelectromechanical systems (MEMS) and nanoelectromechanical systems (NEMS) switch

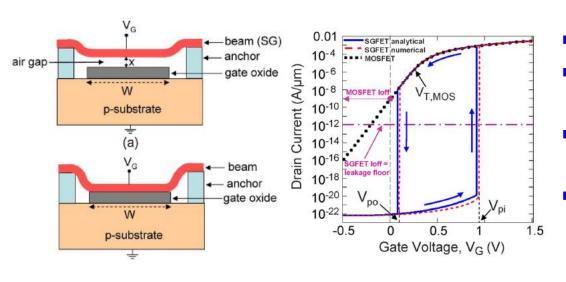
Suspended Gate ('SG') FET





Microelectromechanical systems (MEMS) and nanoelectromechanical systems (NEMS) switch

Suspended Gate ('SG') FET

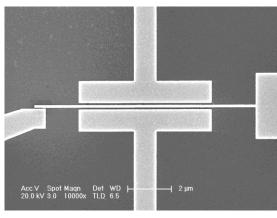


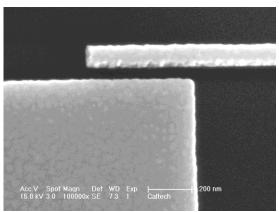
- $V_{\rm pi}$ within $V_{\rm DD}$ of transistor
- V_{pi} at weak inversion/accumulation region
- V_{po} > 0, suspended structure rigid enough
 - Bandwidth consideration Scaling to NEMS dimensions

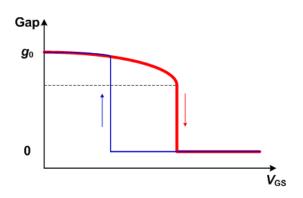
Akarvadar, Eggimann, Tsamados, Chauhan, Wan, Ionescu, Howe, Wong, et al., IEEE Trans. Electron Dev. 55, 48-59 (2008)

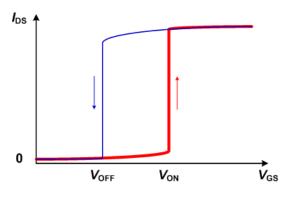
Microelectromechanical systems (MEMS) and nanoelectromechanical systems (NEMS) switch

Pure mechanical switch: cantilever





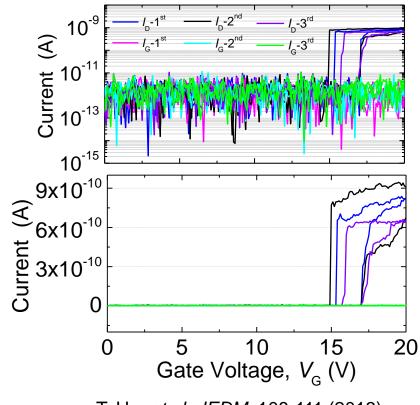




Microelectromechanical systems (MEMS) and nanoelectromechanical systems (NEMS) switch

Pure mechanical switch: cantilever

- Abrupt switching!
- I-V Characteristics
 - Switch-On voltage, V_{On}
 - Switch-Off voltage, V_{Off}
 - On State
 Current/Resistance,
 I_{ON}/R_{ON}
 - Off-State Current



T. He, et al., IEDM, 108-111 (2013)

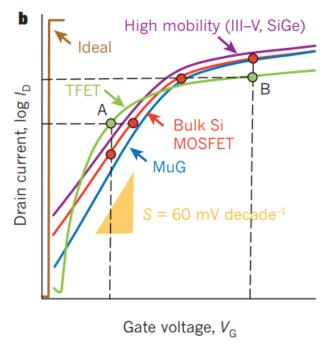
Tunnel FETs

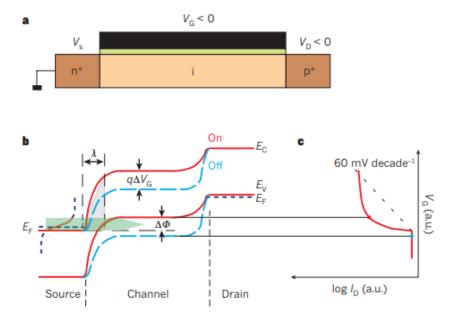
REVIEW

doi:10.1038/nature10679

Tunnel field-effect transistors as energy-efficient electronic switches

Adrian M. Ionescu1 & Heike Riel2





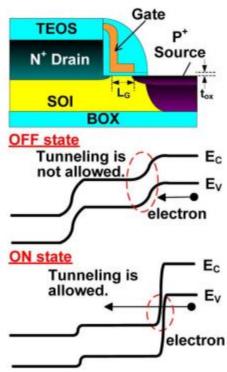
Tunnel FETs

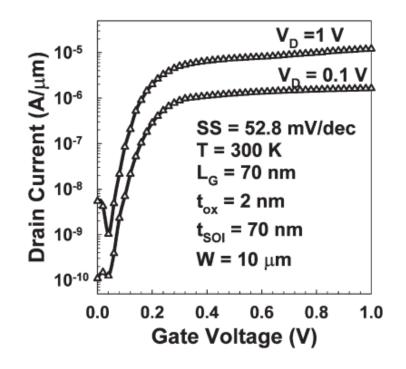
IEEE ELECTRON DEVICE LETTERS, VOL. 28, NO. 8, AUGUST 2007

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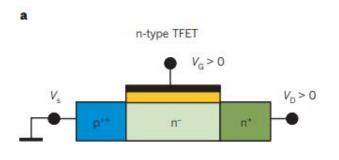
Tunneling Field-Effect Transistors (TFETs) With Subthreshold Swing (SS) Less Than 60 mV/dec

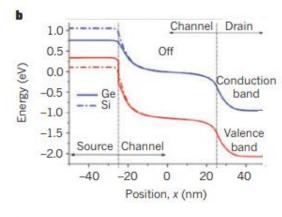
Woo Young Choi, *Member, IEEE*, Byung-Gook Park, *Member, IEEE*, Jong Duk Lee, *Member, IEEE*, and Tsu-Jae King Liu, *Fellow, IEEE*

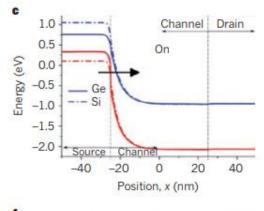


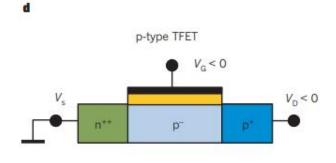


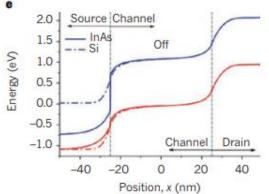
Tunnel FETs

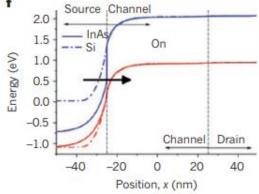




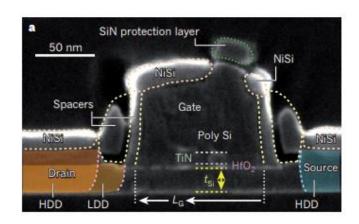


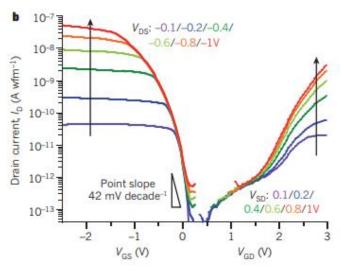




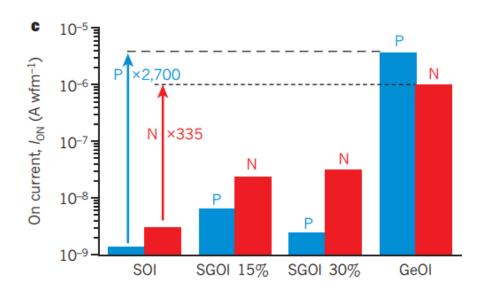


Tunnel FETs

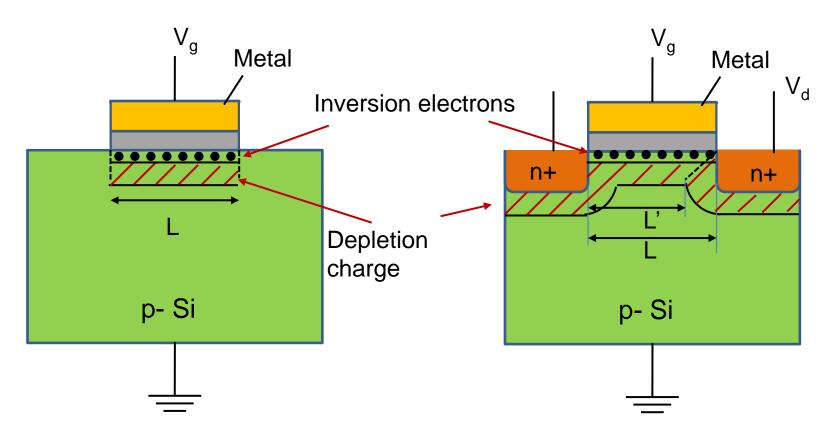




all-Si technology, silicon on insulator (SOI) TFET



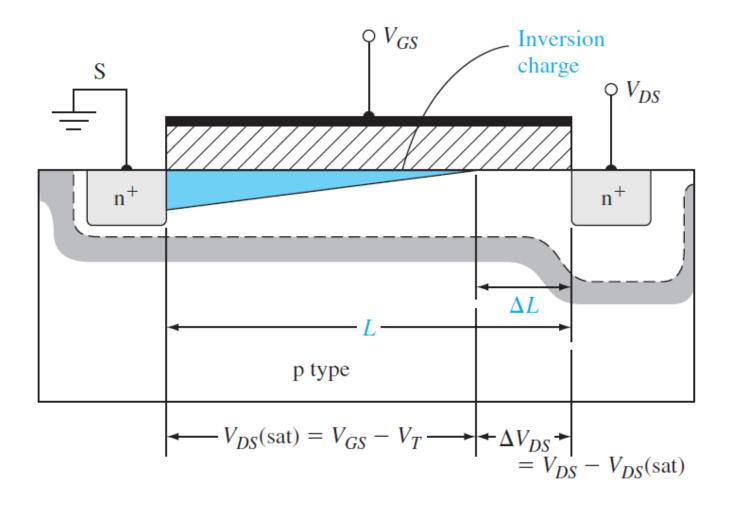
Charge sharing → threshold voltage V_T dependent on V_{ds}



Metal-oxide-semiconductor (MOS)

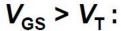
Metal-oxide-semiconductor (MOS)

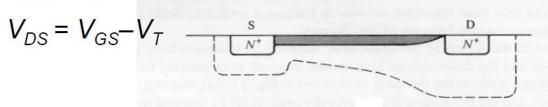
Charge sharing \rightarrow threshold voltage V_T dependent on V_{ds}



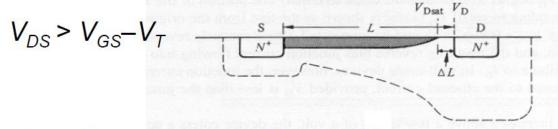
If L is large

What Happens at Larger V_{DS} ?





Inversion-layer is "pinched-off" at the drain end



As V_{DS} increases above $V_{GS} - V_T \equiv V_{DSAT}$

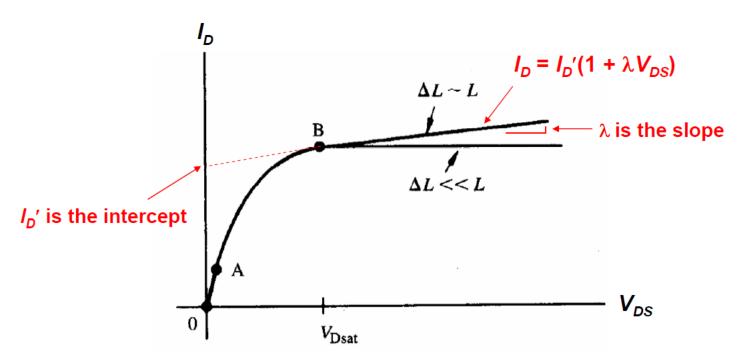
$$I_D = \mu_n C_{ox} \frac{W}{L} \left(V_{GS} - V_T - \frac{1}{2} V_{DS} \right) V_{DS}$$
 I_D will not increase after $V_{ds} \ge V_{gs} - V_T$

$$I_D = \mu_n C_{ox} \frac{W}{L} \left(V_{GS} - V_T - \frac{1}{2} V_{DS} \right) V_{DS} = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} (V_{GS} - V_T) (V_{GS} - V_T)$$

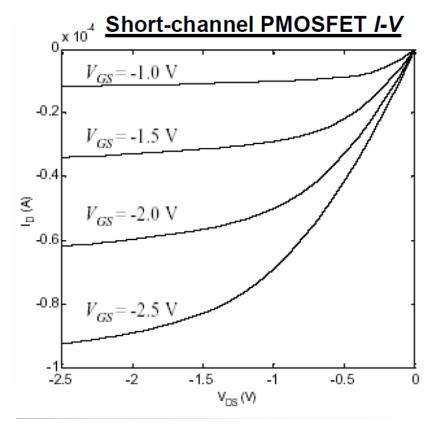
Short channel

If L is small, the effect of ΔL to reduce the inversion-layer "resistor" length is significant

 \rightarrow I_D increases noticeably with ΔL (i.e. with V_{DS})



As compared to an n-channel MOSFET, the signs of all the voltages and the currents are reversed:



Short channel

For a n⁺p junction, essentially all of the applied reverse-biased voltage is across the low-doped p region. Space charge width

$$x_p = \sqrt{\frac{2\epsilon_s}{eN_a} \left(\phi_{fp} + V_{DS}\right)}$$

 ΔL is the total space charge width minus the space charge width that exists when $V_{DS} = V_{DS}$ (sat)

$$\Delta L = \sqrt{\frac{2\epsilon_s}{eN_a}} \left[\sqrt{\phi_{fp} + V_{DS}(\text{sat}) + \Delta V_{DS}} - \sqrt{\phi_{fp} + V_{DS}(\text{sat})} \right]$$
$$\Delta V_{DS} = V_{DS} - V_{DS}(\text{sat})$$

Short channel

Drain current is inversely proportional to the channel length, the actual current

$$I_D' = \left(\frac{L}{L - \Delta L}\right) I_D$$

The output resistance is no longer infinite

$$I'_{D} = \frac{k'_{n}}{2} \cdot \frac{W}{L} \cdot \left[(V_{GS} - V_{T})^{2} (1 + \lambda V_{DS}) \right]$$

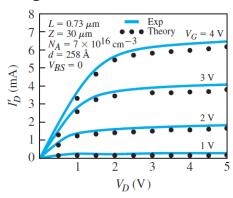
 λ is the channel length modulation parameter

Output resistance

$$r_o = \left(\frac{\partial I_D'}{\partial V_{DS}}\right)^{-1} = \left\{\frac{k_n'}{2} \cdot \frac{W}{L} \cdot (V_{GS} - V_T)^2 \cdot \lambda\right\}^{-1}$$

 λ is usually small

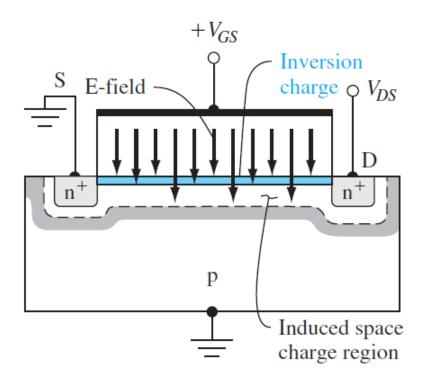
$$r_o \cong \frac{1}{\lambda I_D}$$



MOSFET: Mobility variation

Mobility not a constant

- Variation of mobility with gate voltage
- Effective carrier mobility decreases as the carrier approaches the velocity saturation limit

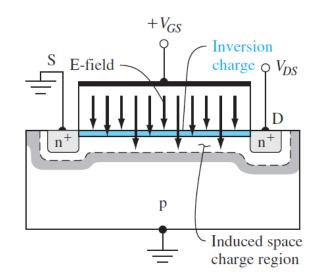


Why mobility changes with gate voltage?

MOSFET: Mobility variation

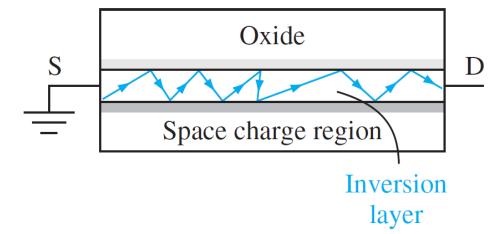
Mobility not a constant

Why mobility changes with gate voltage?
Electrons scatter at the surface, due to coulomb force: surface scattering
If there positive fixed oxide charge near the oxide-semiconductor interface, the mobility will be further reduced due to the additional coulomb interaction



Electric field

$$E_{\text{eff}} = \frac{1}{\epsilon_s} \left(|Q'_{SD} (\text{max})| + \frac{1}{2} Q'_n \right)$$

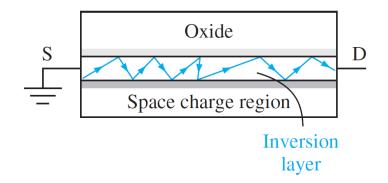


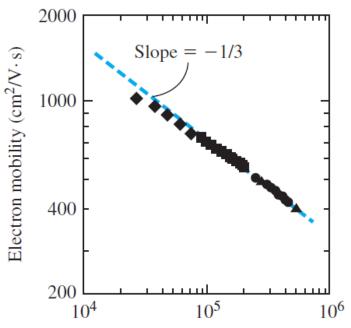
MOSFET: Mobility variation

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$$\mu_{\mathrm{eff}} = \mu_0 \left(\frac{\mathrm{E}_{\mathrm{eff}}}{\mathrm{E}_0}\right)^{-1/3}$$





Effective field in inversion layer, E_{eff} (V/cm)